



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re patent application of

Group Art Unit: 1746

Keum Joo LEE, et al.

Examiner: M. Kornakov

Serial No. 09/955,126

Confirmation No.: 8415

Filed: September 19, 2001

For: METHOD OF CLEANING DAMAGED
LAYERS AND POLYMER RESIDUE
FROM SEMICONDUCTOR DEVICE**PETITION FOR EXTENSION OF TIME**
UNDER 37 C.F.R. § 1.136Commissioner for Patents
P.O. Box 1450
Alexandria, VA. 22313-1450

Sir:

It is respectfully requested that an extension of time for the period indicated below be granted in accordance with the provisions of 37 C.F.R. § 1.136 to take the action required in the application identified in caption, as reflected by the papers submitted herewith.

<u>X</u> First Month	\$110 (\$ 55)*
<u>X</u> Second Month	\$310 (\$155)*
<u>X</u> Third Month	\$530 (\$265)*
<u> </u> Fourth Month	\$530 (\$265)*
<u> </u> Fifth Month	\$530 (\$265)*

*(Small Entity) TOTAL FEE: \$950.00

The Commissioner is hereby authorized to charge the necessary extension fees to our Deposit Account No. 5-01645.

Respectfully submitted,

March 5, 2004
Date
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03/09/2004 MAHME1 00000087 501645 09955126

01 FC:2253 475.00 DA

Void date: 03/09/2004 MAHME1
03/09/2004 MAHME1 00000087 501645 09955126
01 FC:2253 475.00 CR

03/09/2004 MAHME1 00000088 501645 09955126

01 FC:1253 950.00 DA

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